

TECHNICAL SPEC FOR Deposition/Etch tool

System Model: **AMAT Centura Ultima+ HDP-CVD**

Process: **HDP-CVD**

Wafer size: **6"**

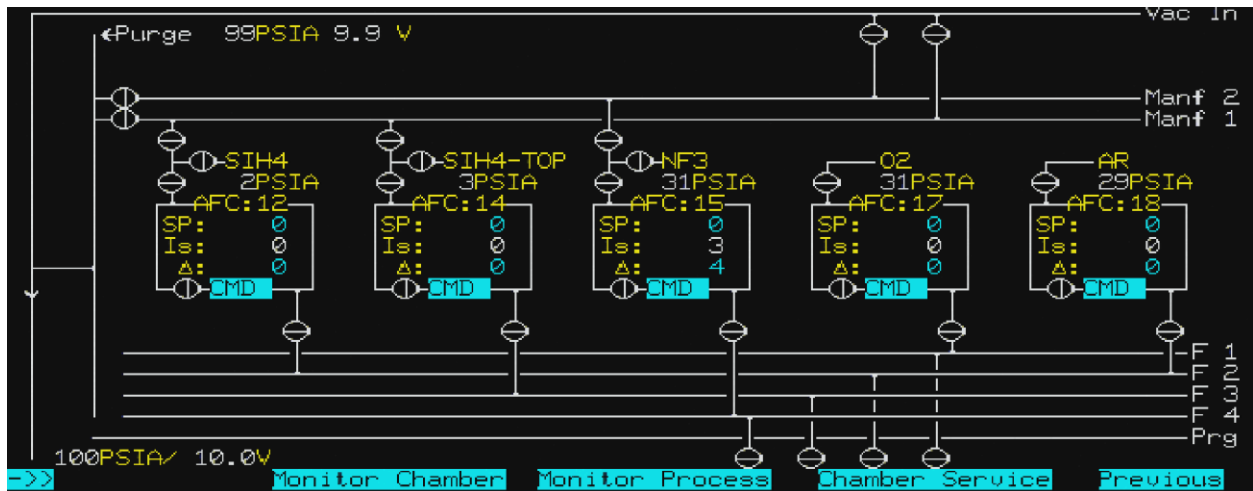
Wafer type: **JMF**

Valve type: **HVA 21251-1003Z-001 gate valve**

Wide/Narrow body: **Narrow body**

Frame: **Chamber A and B – MS Cool Down (E) and Orienter (F)**

Gas and process configuration **identical for all process chambers**



SiH4	//	MFC 200 sccm
SiH4-Top	//	MFC 20 sccm
NF3	//	MFC 3000 sccm
O2	//	MFC 400 sccm
Ar	//	MFC 300 sccm



Vintage: Yes

Missing/defective parts: **None**

Photos to Collect

- All 4 sides
- Robot
- Loader
- Gas lines
- Gas box
- Close up from each chamber
- Turbos and Pumps on each process module
- Bottom of each side (there are VGA's, and a number of other cards on the bottom of the sides of the tool)
- Controllers
- Electrical cabinets
- AC Rack
- Gas in/outlets
- Electrical in/outlets
- Chiller
- Serial plates of all chambers
- Serial plate of Mainframe
- Serial plate of each pump
- Spare parts, manuals (if any)